

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. – 4. (Canceled)

5. (Currently Amended) A system made up of at least one substrate conveying module and at least one workstation which has several side walls, substrates being exchangeable between the substrate conveying module and the workstation, wherein the workstation has, on at least two different side walls, kinematic coupling connecting elements that ~~coact with~~ **are directly connected to** corresponding kinematic coupling connecting elements on at least one side wall of the substrate conveying module to provide for ~~a an~~ **immovable** connection between the workstation and the substrate conveying module while simultaneously automatically aligning the workstation with the substrate conveying module.

6. (Canceled)

7. (Currently Amended) A system made up of at least one substrate conveying module and at least one workstation which has several side walls, substrates being exchangeable between the substrate conveying module and the workstation, wherein the workstation has, on at least two different side walls, kinematic coupling connecting elements that ~~coact with~~ **are directly connected to** corresponding kinematic coupling connecting elements on at least one side wall of the substrate conveying module; wherein the substrate conveying module has one or more load ports for the loading and unloading of the substrates into and from the substrate conveying module.

8. (Previously Presented) The system as defined in Claim 5, wherein the workstation is provided for the inspection, measurement, or processing of the substrates.

9. (Previously Presented) The system as defined in Claim 5, wherein the workstation comprises a permanently set transfer point for the exchange of the substrates between the substrate conveying module and the workstation.

10. – 11. (Canceled)

12. (Previously Presented) The system as defined in Claim 5, wherein the substrate conveying module has kinematic coupling connecting elements on at least two different side walls.

13. (Previously Presented) The system as defined in Claim 12, wherein the substrate conveying module has at least one load port for the loading and unloading of said substrates into and from the substrate conveying module,

wherein said workstation is configured to perform a function comprising at least one of inspecting, measuring, and processing said substrates,

wherein each of said at least two different side walls of said workstation is connectable to each of said at least two different side walls of said substrate conveying module so as to provide for at least four distinct connection configurations between said workstation and said substrate conveying module, and

wherein, in each of said at least four configurations, said system is configured to move said substrates from said at least one load port to said workstation to perform said function.

14. (Previously Presented) The system as defined in Claim 5, wherein the at least two different side walls are adjacent.

15. (Previously Presented) The system as defined in Claim 5, wherein the workstation is configured to exchange said substrates with said substrate conveying module via only one of said at least two different side walls at a time.

16. (Previously Presented) The system as defined in Claim 5, wherein said substrate conveying module is a first substrate conveying module,

wherein said system further comprises a second substrate conveying module,

wherein each of said substrate conveying modules has kinematic coupling connecting elements on at least two different side walls,

wherein each of said substrate conveying modules is connected to said workstation,
and

wherein said system is configured so that substrates are exchanged from said first substrate conveying module to said workstation, and subsequently from said workstation to said second substrate conveying module.

17. (Cancelled)

18. (Cancelled)

19. (Cancelled)

20. (Previously Presented) The system as defined in Claim 5, wherein the substrate conveying module has one or more load ports for the loading and unloading of the substrates into and from the substrate conveying module.

21. (New) A system made up of at least one substrate conveying module and at least one workstation which has several side walls, substrates being exchangeable between the substrate conveying module and the workstation, wherein the workstation has, on at least two different side walls, kinematic coupling connecting elements that are directly connected to corresponding kinematic coupling connecting elements on at least one side wall of the substrate conveying module to provide for a connection between the workstation and the substrate conveying module, wherein

the system is adapted to provide a substantially variable and substantially flexible arrangement of the substrate conveying module with respect to the workstation at a user's site.

22. (New) The system as defined in Claim 21, wherein the workstation is provided for the inspection, measurement, or processing of the substrates.

23. (New) The system as defined in Claim 21, wherein the workstation comprises a permanently set transfer point for the exchange of the substrates between the substrate conveying module and the workstation.

24. (New) The system as defined in Claim 21, wherein the substrate conveying module has kinematic coupling connecting elements on at least two different side walls.

25. (New) The system as defined in Claim 24, wherein the substrate conveying module has at least one load port for the loading and unloading of said substrates into and from the substrate conveying module,

wherein said workstation is configured to perform a function comprising at least one of inspecting, measuring, and processing said substrates,

wherein each of said at least two different side walls of said workstation is connectable to each of said at least two different side walls of said substrate conveying module so as to provide for at least four distinct connection configurations between said workstation and said substrate conveying module, and

wherein, in each of said at least four configurations, said system is configured to move said substrates from said at least one load port to said workstation to perform said function.

26. (New) The system as defined in Claim 21, wherein the at least two different side walls are adjacent.

27. (New) The system as defined in Claim 21, wherein the workstation is configured to exchange said substrates with said substrate conveying module via only one of said at least two different side walls at a time.

28. (New) The system as defined in Claim 21, wherein said substrate conveying module is a first substrate conveying module,

wherein said system further comprises a second substrate conveying module,

wherein each of said substrate conveying modules has kinematic coupling connecting elements on at least two different side walls,

wherein each of said substrate conveying modules is connected to said workstation,
and

wherein said system is configured so that substrates are exchanged from said first substrate conveying module to said workstation, and subsequently from said workstation to said second substrate conveying module.

29. (New) The system as defined in Claim 21, wherein the substrate conveying module has one or more load ports for the loading and unloading of the substrates into and from the substrate conveying module.

30. (New) The system as defined in Claim 21, wherein the system is adapted to provide a substantially variable and substantially flexible arrangement of the substrate conveying module with respect to the workstation at an installation location of the system after the substrate conveying module is connected to the workstation.